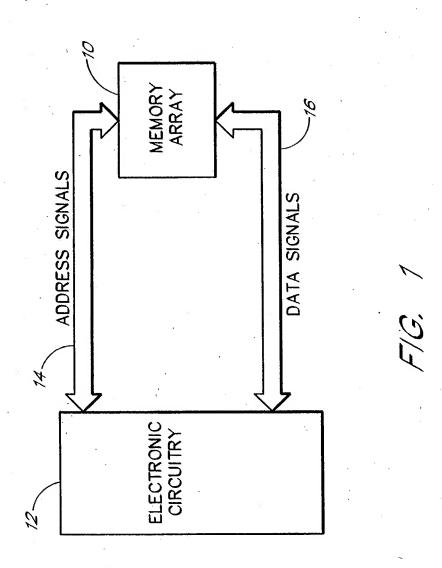
SEMICONDUCTOR STRUCTURE WITH SUBSTANTIALLY ETCHED
OXYNITRIDE....
Gary Chen et al.
Appl. No.: Unknown Atty Docket: MICRON.109DC1D1

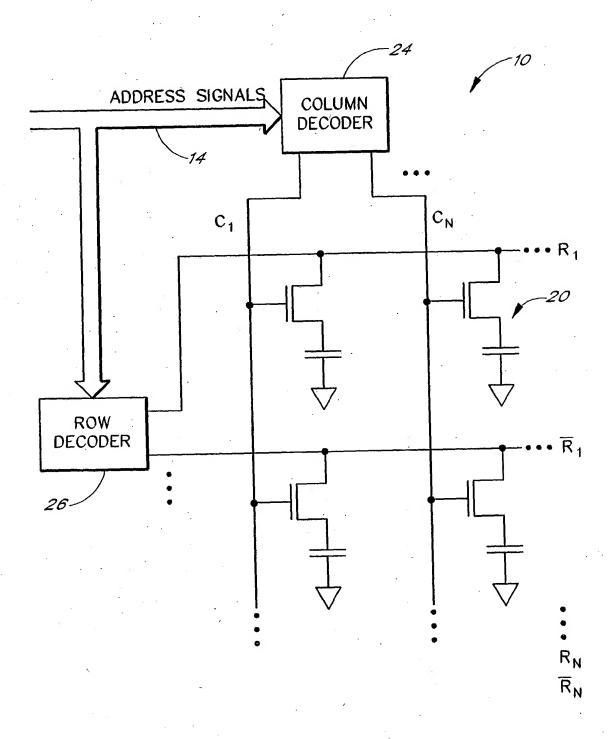


$SEMICONDUCTOR\ STRUCTURE\ WITH\ SUBSTANTIALLY\ ETCHED\\ OXYNITRIDE....$

Gary Chen et al.

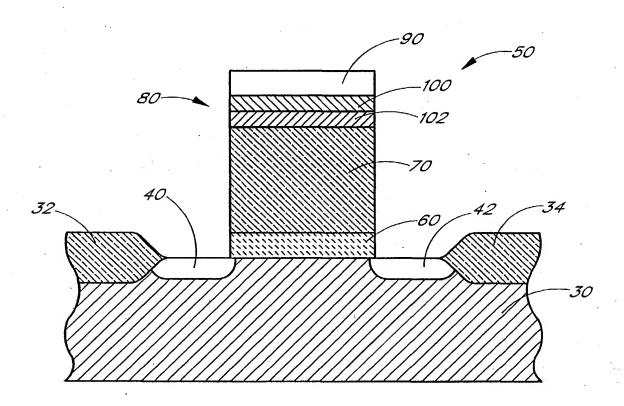
Appl. No.: Unknown

Atty Docket: MICRON.109DC1D1



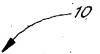
SEMICONDUCTOR STRUCTURE WITH SUBSTANTIALLY ETCHED
OXYNITRIDE....
Gary Chen et al.
Appl. No.: Unknown Atty Docket: MICRON.109DC1D1

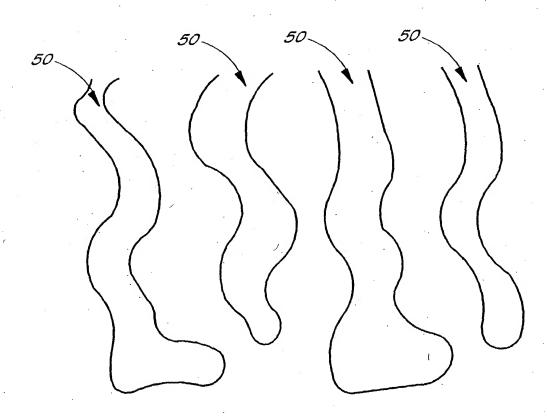
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F/G. 3

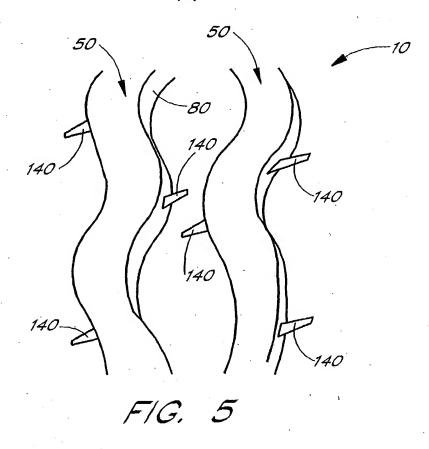
SEMICONDUCTOR STRUCTURE WITH SUBSTANTIALLY ETCHED
OXYNITRIDE....
Gary Chen et al.
Appl. No.: Unknown Atty Docket: MICRON 109DC1D1

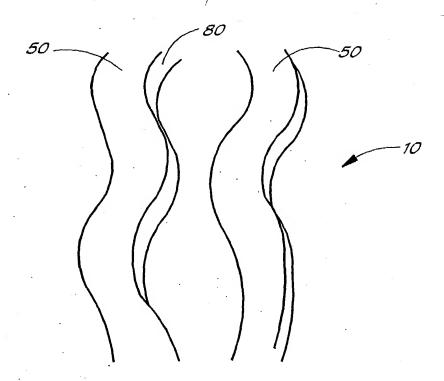




F/G. 4

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OXYNITRIDE....
Gary Chen et al.
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Gary Chen et al.

Appl. No.: Unknown

Atty Docket: MICRON.109DC1D1

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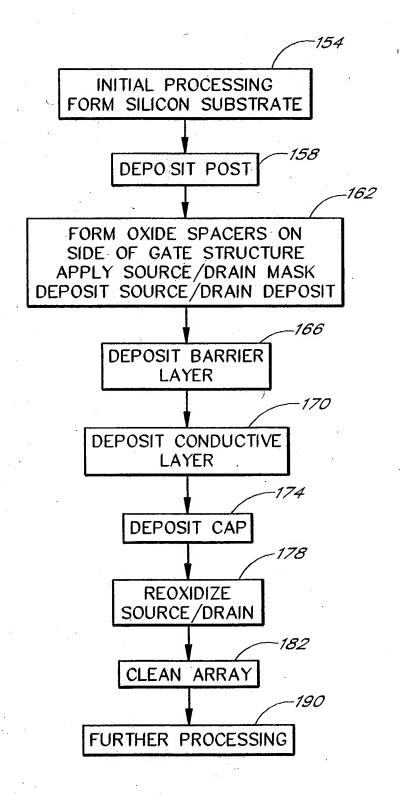


FIG. 7